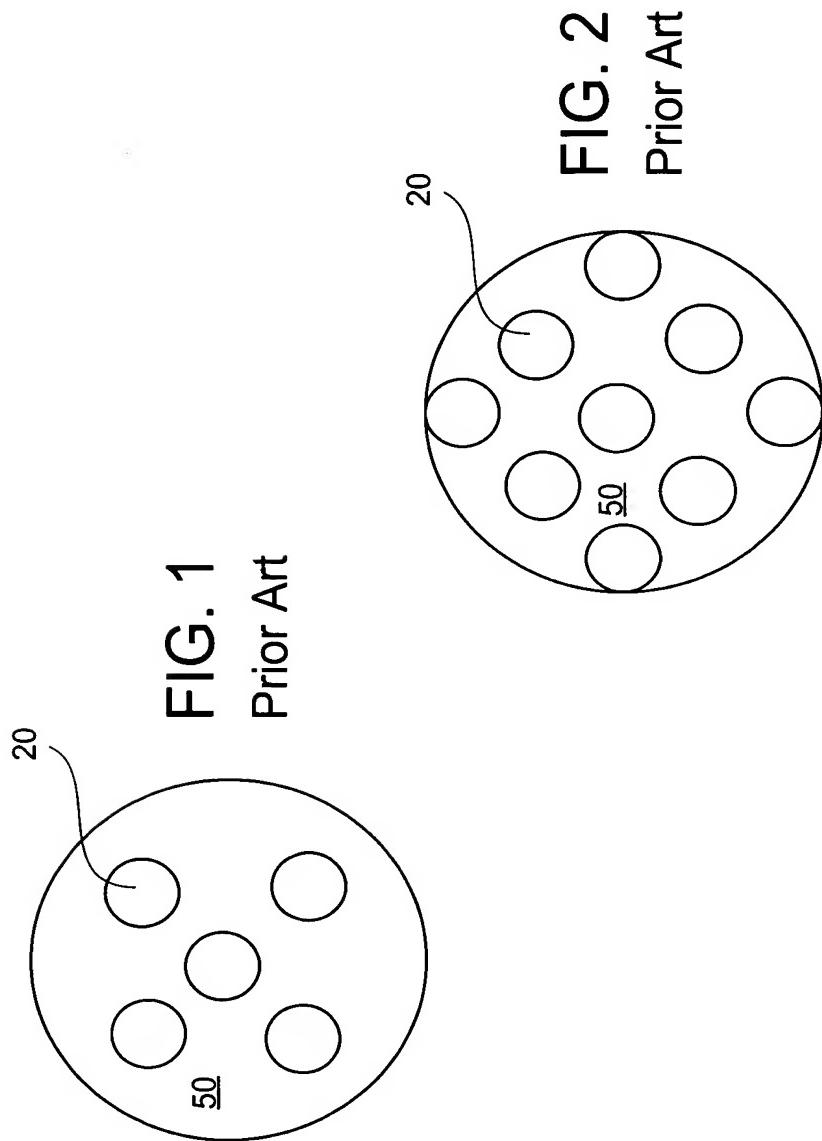




Title: METHOD AND APPARATUS FOR MEASUREMENT OF THIN FILMS  
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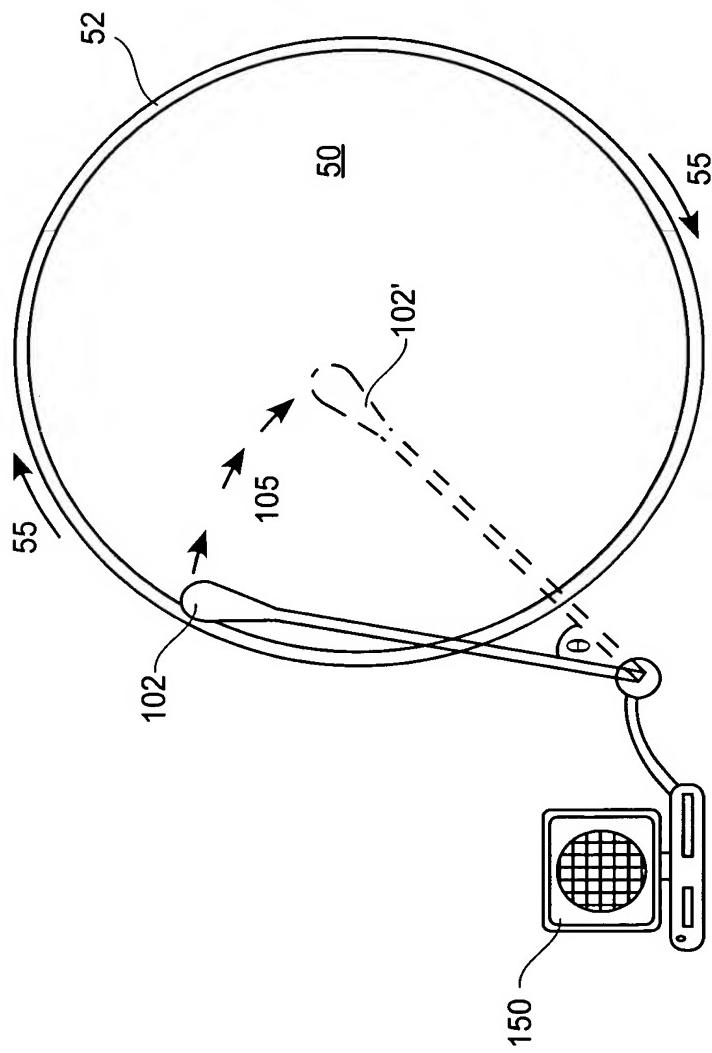


FIG. 3

FIG. 4B

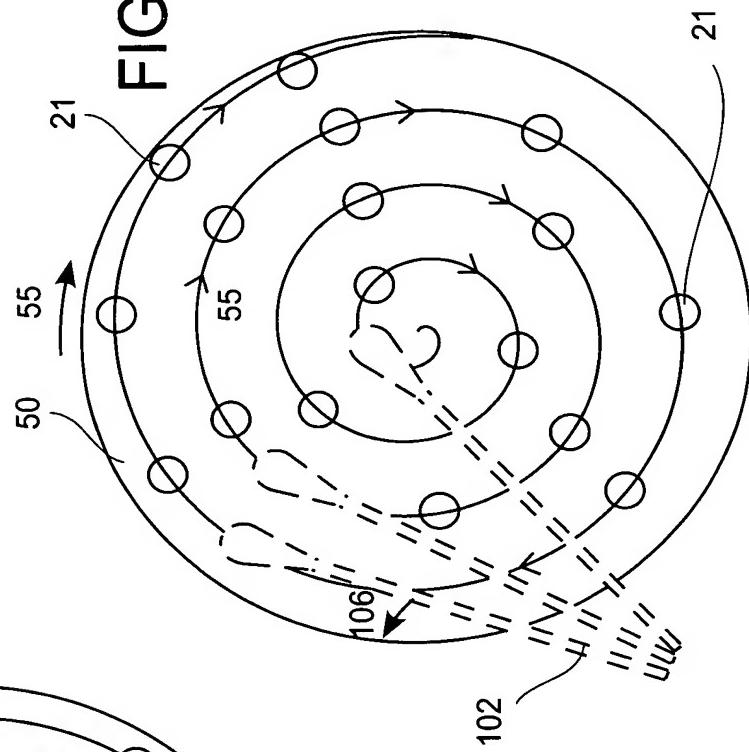
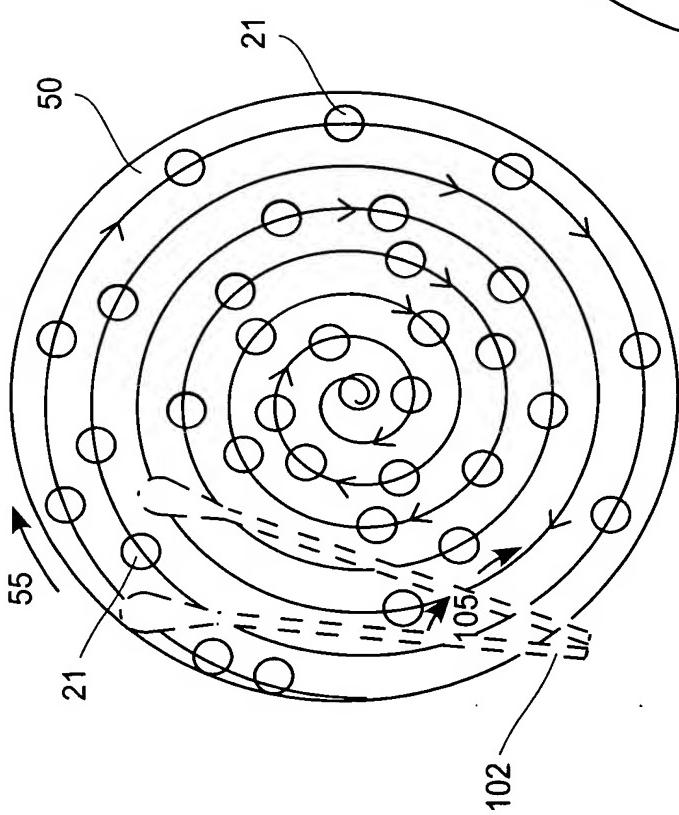


FIG. 4A



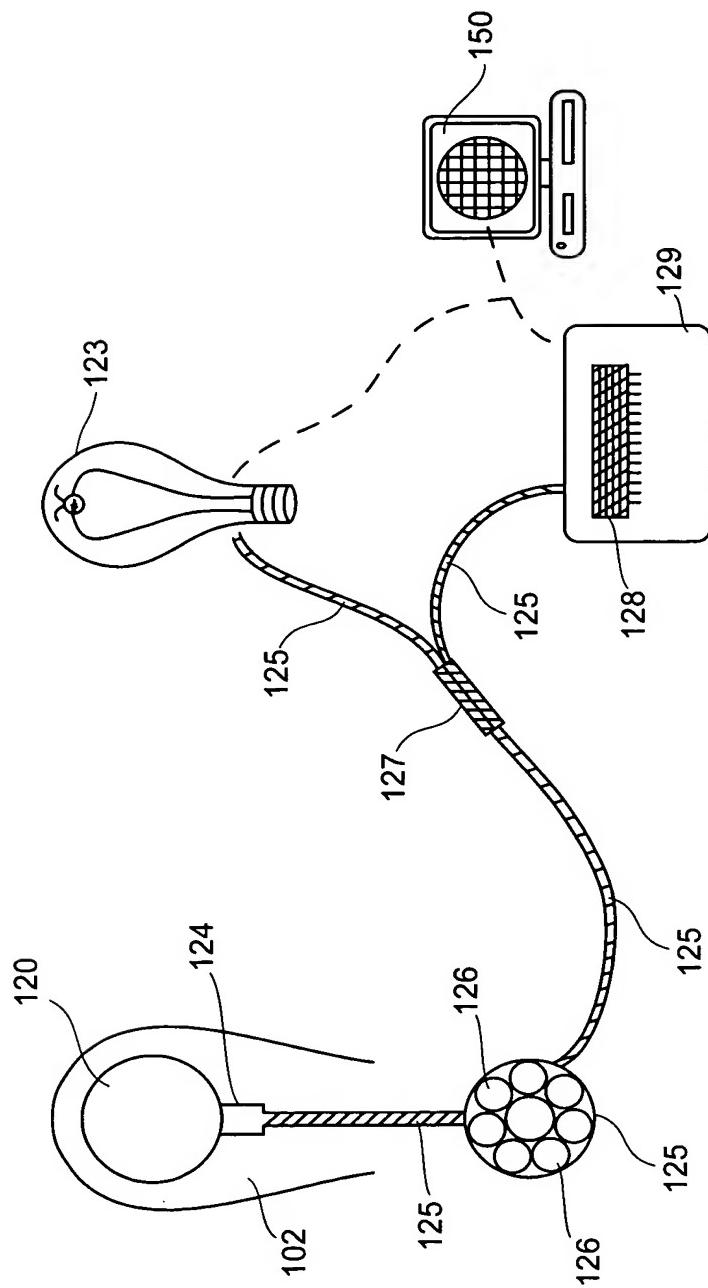
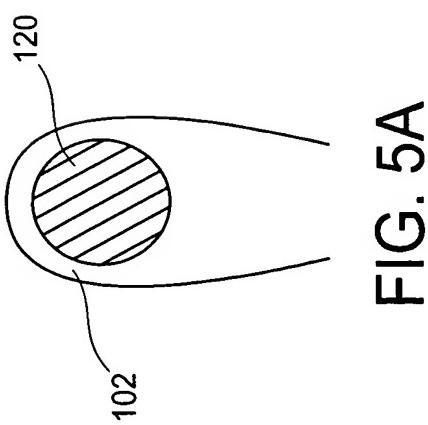
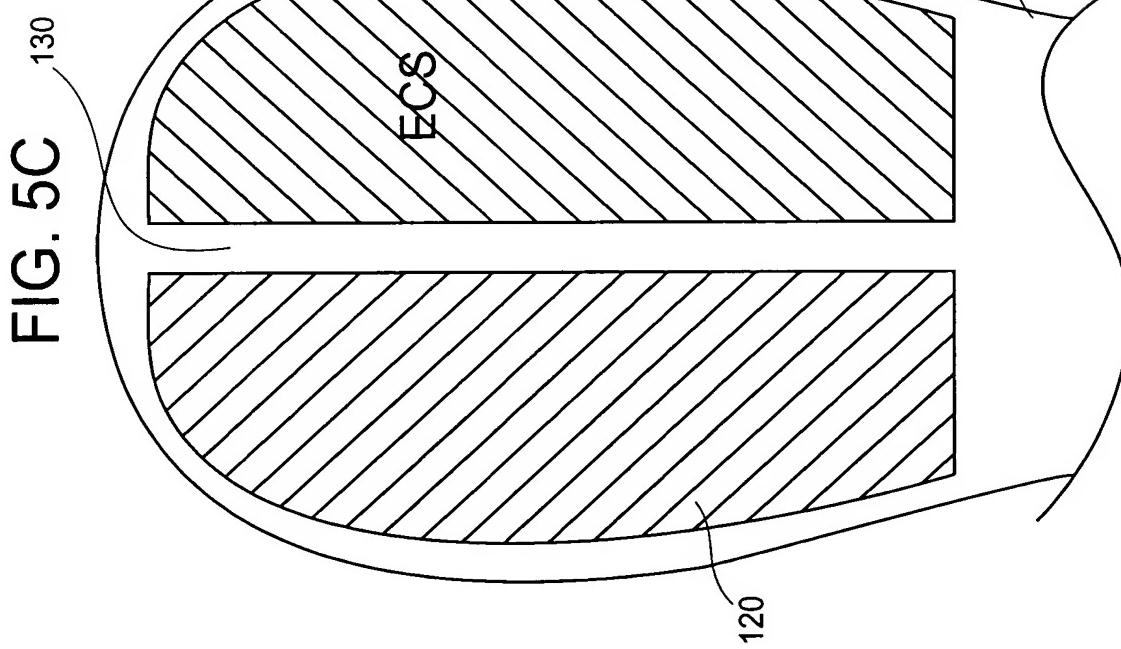
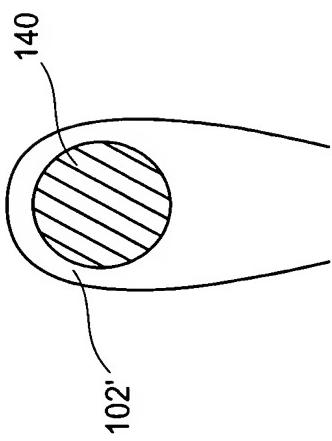


FIG. 5A-1



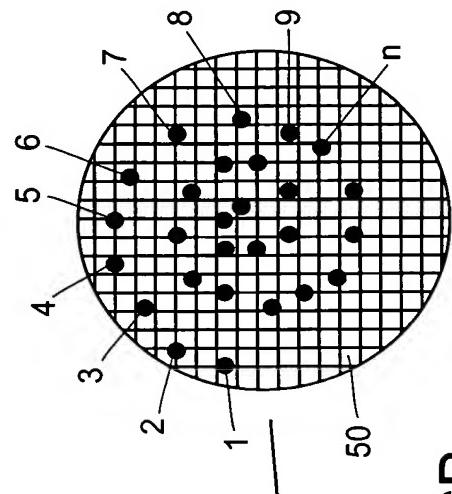
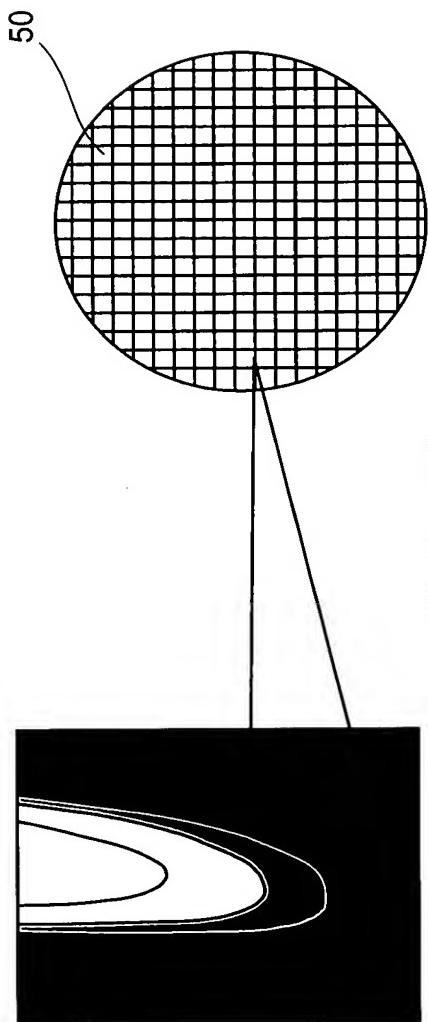


FIG. 6B

	A	B
1	xx yy zz aa bb cc	yy zz aa bb cc
2	xx yy zz aa bb cc	yy zz aa bb cc
3	xx yy zz aa bb cc	yy zz aa bb cc
4	xx yy zz aa bb cc	yy zz aa bb cc
5	xx yy zz aa bb cc	yy zz aa bb cc
6	xx yy zz aa bb cc	yy zz aa bb cc
7	xx yy zz aa bb cc	yy zz aa bb cc
8	xx yy zz aa bb cc	yy zz aa bb cc
9	xx yy zz aa bb cc	yy zz aa bb cc
n	xx yy zz aa bb cc	yy zz aa bb cc

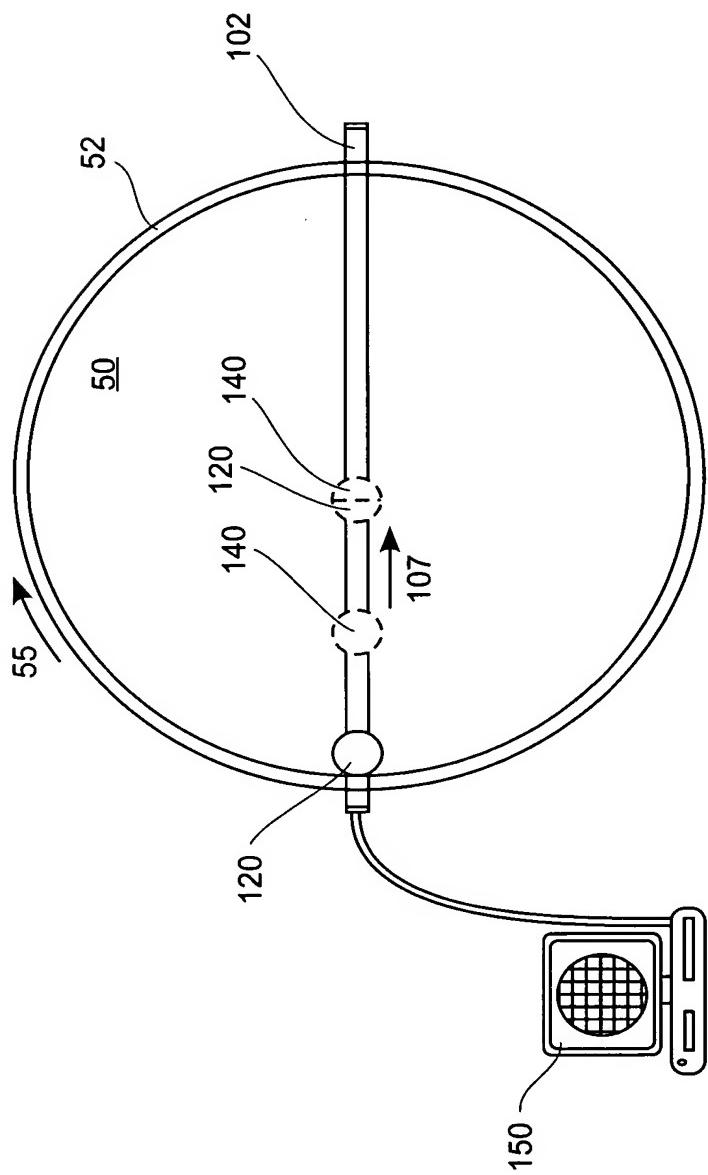


FIG. 7

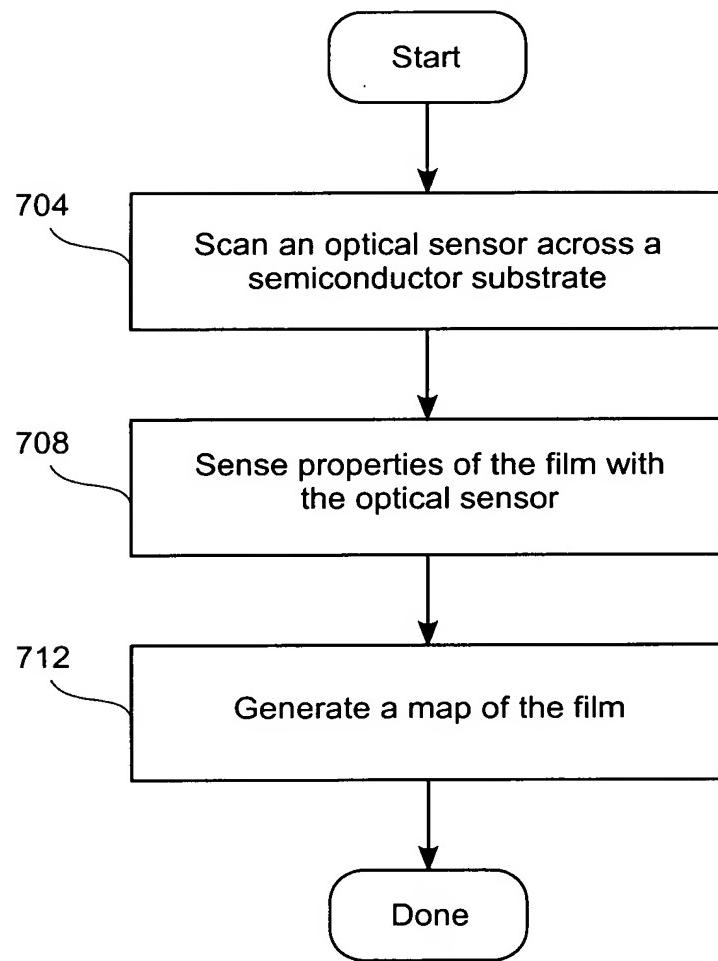
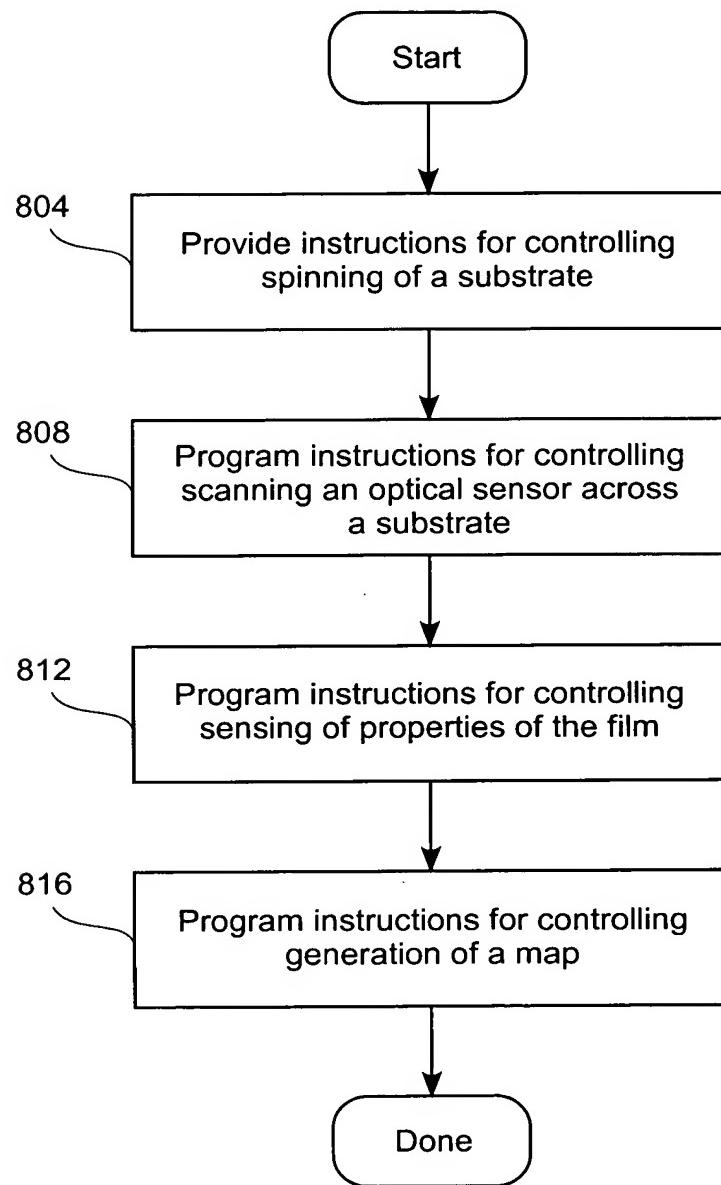


FIG. 8



**FIG. 9**